



Patent

Attorney's Docket No. 015290-502

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of) **BOX AF**
Helen H. ZHU et al.)
Application No.: 09/820,694) Group Art Unit: 2823
Filed: March 30, 2001) Examiner: J. J. Maldonado
For: METHOD OF PLASMA ETCHING) Confirmation No.: 7374
SILICON NITRIDE)

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PETITION FOR EXTENSION OF TIME

Assistant Commissioner for Patents
Washington, D.C. 20231

Sir:

The following extension of time is requested to extend the time for responding to the Official Action dated December 4, 2002 :

one month to April 1, 2003 ; the extension fee is:

☐ \$55.00 (2251) ☒ \$110.00 (1251).

☐ The shortened statutory period has been reset by an Advisory Action dated _____.

☐ An extension fee in the amount of \$_____ is enclosed.

☒ Charge \$ 110.00 to Deposit Account No. 02-4800.

The Commissioner is hereby authorized to charge any appropriate fees under 37 C.F.R. §§ 1.16, 1.17 and 1.21 that may be required by this paper, and to credit any overpayment, to Deposit Account No. 02-4800. This paper is submitted in duplicate.

Respectfully submitted,

BURNS, DOANE, SWECKER & MATHIS, L.L.P.

Date: April 1, 2003

By: Peter K. Skiff
Peter K. Skiff
Registration No. 31,917

P.O. Box 1404
Alexandria, Virginia 22313-1404

(703) 836-6620

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